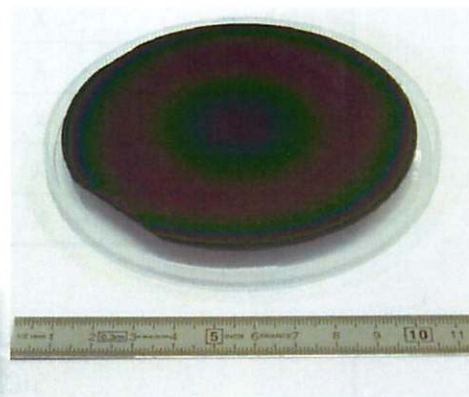




Heteroepitaxial cubic SiC layers on silicon.

Material specifications

| Substrate ¹⁾ | | Si, SOI | |
|--|--------------------------------|--|--|
| Orientation | | (100) | (111) |
| Substrate diameter | | 100mm | 100mm |
| Other substrate properties (thickness, resistivity, miscut ...) | Following the client's request | | |
| Layer | | 3C-SiC | |
| Orientation | | (100) | (111) |
| Thickness range ²⁾ | | 0 - 20µm | 0 - 1µm; Cracks >1µm |
| Thickness variation ²⁾ (σ/mean) | | ≤ 10% | |
| Electrical conductivity | | n type | |
| Unintentional doping ³⁾ (N _D -N _A) | | ≤ 1×10 ¹⁴ cm ⁻³ | |
| Al incorporation ⁴⁾ | | ≤ 1×10 ¹⁵ cm ⁻³ | |
| Voluntary doping | | Nitrogen | |
| Doping range ^{3),4)} | | 1×10 ¹⁶ - 1×10 ¹⁹ cm ⁻³ | 5×10 ¹⁶ - 5×10 ¹⁸ cm ⁻³ |
| Doping variation ^{3),4)} (σ/mean) | | ≤ 50% | |
| Protrusion density ⁵⁾ | | ≤ 3×10 ³ cm ⁻² | |
| Other services - on client's request | | | |
| Epiwafer polishing | | Frontside: 1Å<RMS roughness <10Å ⁶⁾ . Backside: Optical. | |
| Detailed report on the layer properties | | FTIR, XRD, SEM and AFM results ⁷⁾ | |



- 1) If necessary, wafers may be supplied by NOVASIC
- 2) Detailed thickness profile obtained by FTIR spectrometry
- 3) Carrier concentration calculated from C-V measurements
- 4) Dopant incorporation deduced from SIMS measurements
- 5) Microscopic inspection of crystallites or other macro-defects
- 6) Polishing under development for 100mm (111) oriented epiwafers.
- 7) SEM images on 2" and 3" wafers

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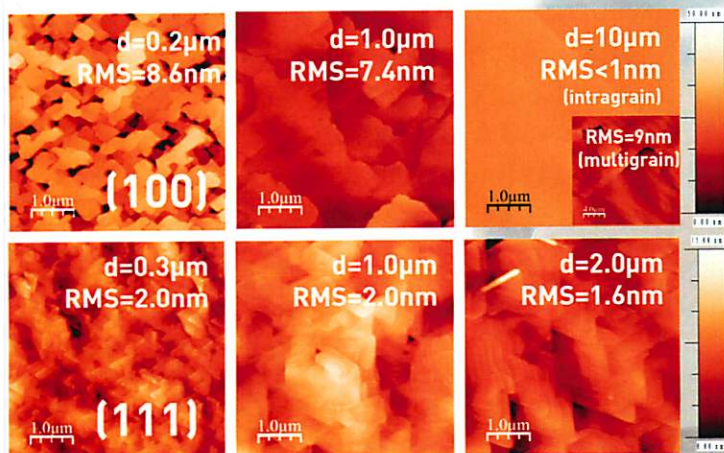


Polished 3C-SiC layers

Best surface preparation before further processing

As-grown morphology - rough surface

Growth mode (3D islands) is at the origin of rough surfaces of as-grown (100) and (111) oriented 3C-SiC *on-axis* layers.



Polished film - low roughness



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Available services

| | SiC | AlN | GaN | Al ₂ O ₃ | ZnO | Ge, CdTe, SiGe silica... |
|---------------|-----|-----|-----|--------------------------------|-----|-----------------------------|
| Polishing | X | X | X | X | X | X |
| Reclaim | X | X | X | X | X | X |
| Thinning | X | | | | | |
| Planarization | X | X | X | | | |
| Epitaxy | X | | | | | |

Surface quality

| | SiC | | | | | | | Other materials | | | | | | |
|------------|------------------------------------|-------|------------------------------------|-------|-----------------------------|-------|-------|--|-------|-------|-----|---|---------------------------------------|---|
| | 4HN - 4HSI On-axis to 8° off | | 6HN - 6HSI On axis to 8° off | | 4H - 6H a- & m- plane | 3C | | Al ₂ O ₃ c- & r- plane | ZnO | | AlN | | GaN c- a -& m-plane | |
| | Si | C | Si | C | N/A | (100) | (111) | N/A | Zn | O | Al | N | Ga | N |
| face | | | | | | | | | | | | | | |
| RMS (Å) | < 1 * | < 1 * | < 1 * | < 1 * | < 1 * | < 2 * | < 7 | < 2 * | < 1 * | < 1 * | < 3 | - | < 2 Depending on orientation | 1 |

* : with atomic steps

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Please feel free to contact us for any further information you may need.

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